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APPARATUS AND METHOD FOR TREATING EXHAUST EMISSION

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Applicant:

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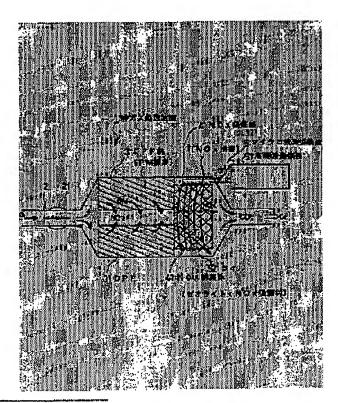
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Abstract of JP2002115531

PROBLEM TO BE SOLVED: To provide an apparatus and a method for treating exhaust emission, capable of attaining compactness and high energy efficiency and regenerating catalysts of which activity has been lost. SOLUTION: Apparatuses 1, 1A for treating exhaust emission, having NOx scavenger scavenging nitrogen oxides in exhaust emission, is formed out of a microwave oscillator 5 irradiating microwaves to the NOx scavenger 4, or the NOx scavenger 4 or a plasma generator 6 generating plasma in the exhaust emission flowing into the NOx scavenger 4.



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